



Docket No. 56775 (70551)

#9  
NA  
8/4/03

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANT: N. Kanetsuki, et al.  
U.S.S.N.: 10/015,446  
FILED: 12/12/2001  
FOR: Plasma Processing Method

EXAMINER: L. Vinh

ART UNIT: 1765

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**CERTIFICATE OF MAILING**

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By:

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**RESPONSE TO OFFICE ACTION**

The following is in response to the Office Action mailed February 21, 2003, in the above referenced application.